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By:

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September 11, 2003

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\$ 2823

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alfred Kersch
Applic. No. : 10/047,814
Filed : January 15, 2002
Title : Reaction Chamber for Processing a Substrate
Wafer, and Method for Operating the Chamber
Examiner : William D. Coleman
Group Art Unit : 2823

A M E N D M E N T

Hon. Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated June 11, 2003 kindly
amend the above-identified application as follows:

09/16/2003 SSESHE1 00000034 10047814

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